

<b>Notice of References Cited</b>		Application/Control No.	Applicant(s)/Patent Under Reexamination	
		10/728,172	GATTIKER ET AL.	
Examiner		Art Unit		Page 1 of 1
Leigh Marie Garbowski		2825		

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,941,235	09-2005	Gattiker, Anne Elizabeth	702/64
*	B	US-6,801,049	10-2004	Ishida et al.	324/765
*	C	US-6,574,760	06-2003	Mydill, Marc	714/724
*	D	US-6,184,048	02-2001	Ramon, Joseph	438/14
*	E	US-6,140,832	10-2000	Vu et al.	324/765
*	F	US-5,467,291	11-1995	Fan et al.	703/14
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)			
*	U	GATTIKER et al., "Current Signatures," 14th VLSI Test Symposium, IEEE 1996, pages 112-117.			
*	V	MAXWELL et al., "Current Ratios: A Self-Scaling Technique for Production IDDQ Testing," ITC Int'l Test Conference, IEEE 1999, pages 738-746.			
	W	MILLER et al., "IDDQ Testing in Deep Submicron ICs," ITC Int'l Test Conference, IEEE 1999, pages 724-729.			
	X	SODEN et al., "IDDQ Testing and Defect Classes - A Tutorial," IEEE 1995 Custom ICs Conference, pages 633-642.			

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)

Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.